

**University of California**  
**College of Engineering**  
**Department of Electrical Engineering and Computer Sciences**

EECS 40  
Introduction to Microelectronic Circuits

Fall 2003  
Prof. King

**FINAL EXAMINATION**

December 10, 2003

Time allotted: 2 hours 50 minutes (170 minutes)

**Name:** \_\_\_\_\_ , \_\_\_\_\_  
(print)                                      **Last**                                      **First**

**Signature:** \_\_\_\_\_                                      **STUDENT ID#:** \_\_\_\_\_

1. This is a **CLOSED BOOK** exam. However, you may use 3 sheets of notes and a calculator.
2. **SHOW YOUR WORK or REASONING** on this exam.  
(Make your methods clear to the grade.)
3. **Write your answers clearly (legibly) in the spaces (lines, boxes, or plots) provided.**
4. Remember to specify the units on answers whenever appropriate.

**SCORE:**    1 \_\_\_\_\_ /20

2 \_\_\_\_\_ /20

3 \_\_\_\_\_ /20

4 \_\_\_\_\_ /20

5 \_\_\_\_\_ /20

6 \_\_\_\_\_ /20

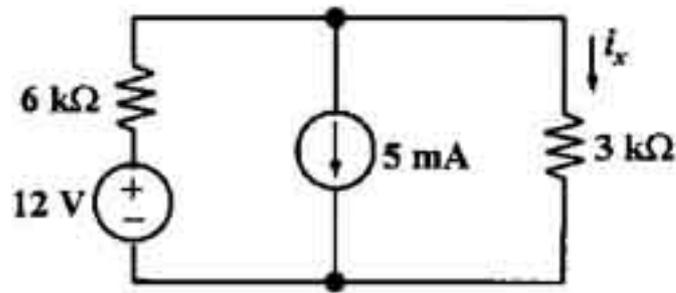
7 \_\_\_\_\_ /20

8 \_\_\_\_\_ /10

Total: \_\_\_\_\_ /150

**Problem 1: Circuit Analysis and Equivalent Circuits [20 points in total]**

a) Consider the following circuit:



i) Use a source transformation in order to find  $i_x$ . [6 pts]

$$i_x = \underline{\hspace{10em}}$$

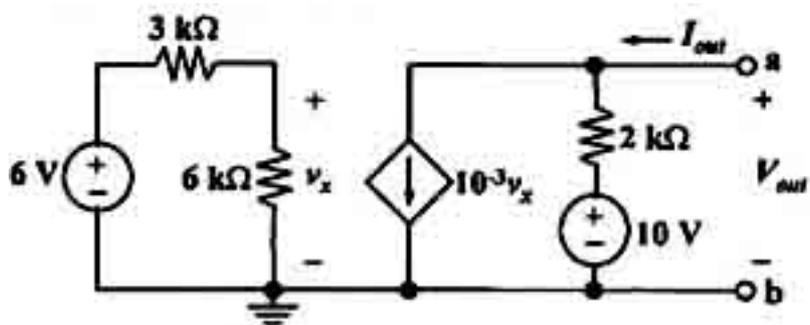
ii) What is the power developed/absorbed by the 5mA current source? [3 pts]

$$\text{Power} = \underline{\hspace{10em}}$$

[developed/absorbed]  
(circle the correct choice)

**Problem 1 (continued)**

b) Consider the following circuit:

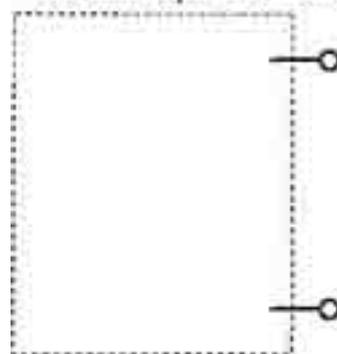


i) Find  $V_{out}$ . [6 pts]

$V_{out} =$  \_\_\_\_\_

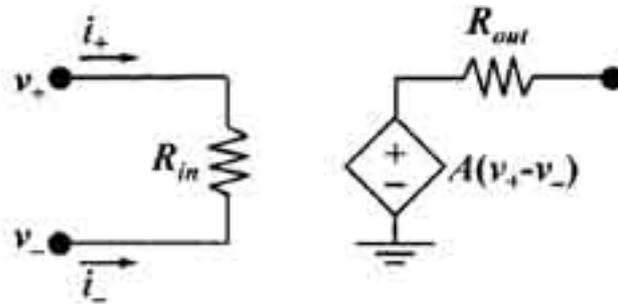
ii) Draw the Thevenin Equivalent circuit [5 pts]

Thevenin Equivalent Circuit:



**Problem 2: Op Amp Circuit [20 points in total]**

a) The following is the circuit model for an op amp circuit operating in its linear region:

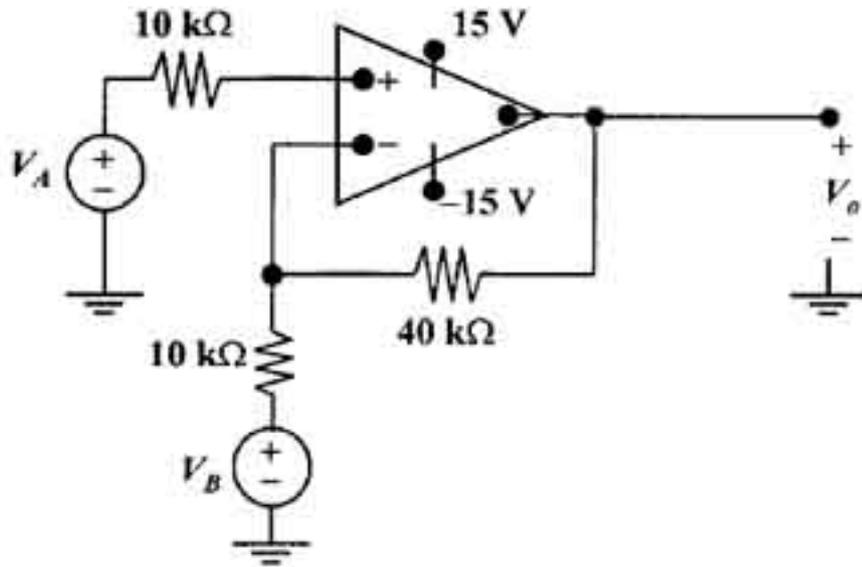


Typically,  $R_{in}$  is very large ( $\sim 1\text{-M}\Omega$ ),  $A$  is very large ( $>10^4$ ), and  $R_{out}$  is very small ( $<100\Omega$ ).

What type of feedback is used in an op amp circuit, in order to ensure that the op amp will operate in its linear region? Illustrate (with a simple diagram) how this is achieved. [5pts]

**Problem 2 (continued)**

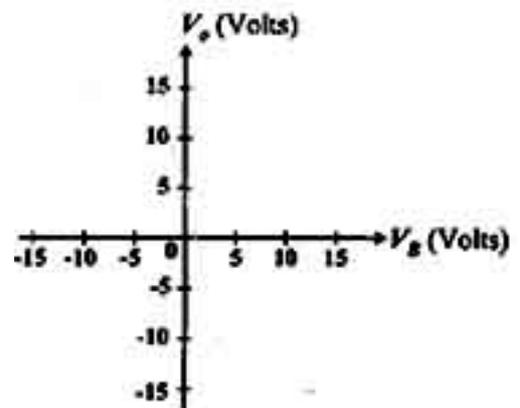
b) Consider the following op amp circuit below. You can assume that the op amp is ideal.



i) Find an expression for  $V_o$ , using superposition. [10pts]

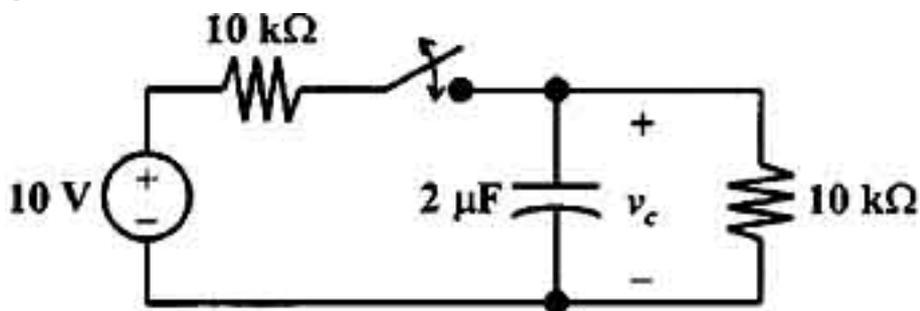
$V_o =$  \_\_\_\_\_

ii) Suppose  $V_A$  is fixed at 1 Volt. Plot  $V_o$  vs  $V_B$  [5 pts]



**Problem 3: First –Order Circuits [20 points in total]**

In the circuit below, the switch is open for all  $t < 0$ . The switch is closed at  $t = 0$ , and then it is open again at  $t = 10\text{ms}$ .



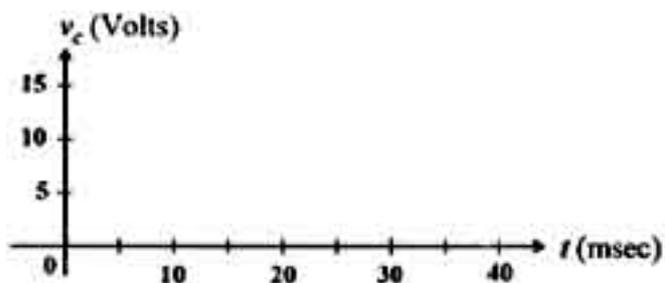
i) Write an equation for  $v_c(t)$ , for  $0 \leq t \leq 10\text{ms}$ . [8 pts]

$0 \leq t \leq 10\text{ms}$ :  $v_c(t) =$  \_\_\_\_\_

ii) Write an equation for  $v_c(t)$ , for  $t > 10\text{ms}$ . [8pts]

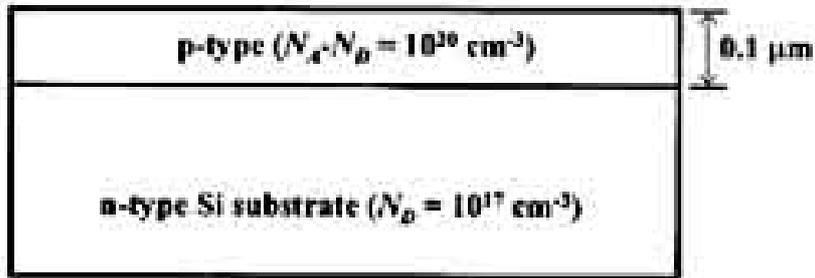
$t > 10\text{ms}$ :  $v_c(t) =$  \_\_\_\_\_

iii) Sketch  $v_c(t)$  for  $t > 0$  [4pts]



**Problem 4: pn junctions; diode [20 points in total]**

- a) Consider a pn junction formed in the surface of an n-type silicon wafer maintained at  $T = 300\text{K}$ . The p and n regions are uniformly doped, as indicated in the figure below:



Schematic cross-sectional view of pn junction

In the p-type region, the electron mobility is  $100 \text{ cm}^2/\text{V s}$  and the hole mobility =  $50 \text{ cm}^2/\text{V s}$

- i) Estimate the sheet resistance of the p-type region [6 pts]

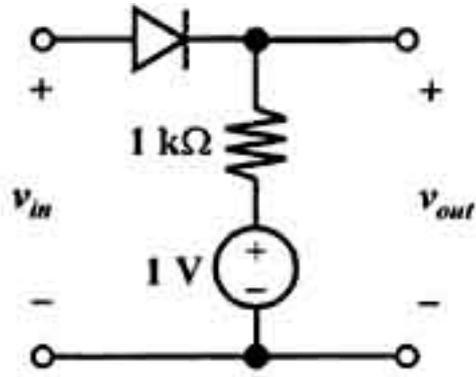
(Use the following values of constants:  $q = 1.6 \times 10^{-19} \text{ C}$ ,  $n_i = 10^{10} \text{ cm}^{-3}$ )

Sheet resistance = \_\_\_\_\_

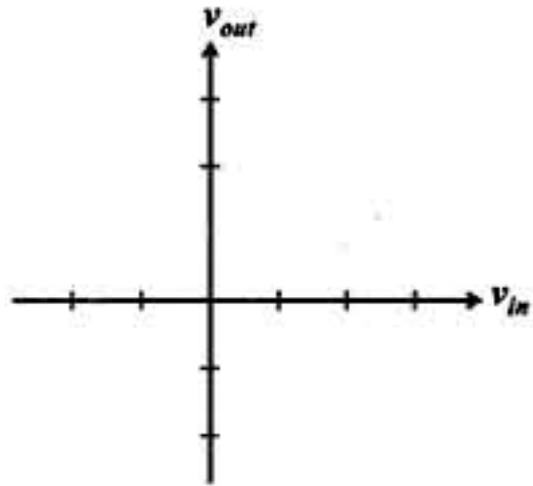
- ii) Suppose the p-type region values serves as the drain region of a p-channel MOSFET in a CMOS inverter, and that the n-type substrate is therefore biased at the power-supply voltage  $V_{DD}$ . How will the pn-junction capacitance change as PMOSFET is turned on (so that the drain bias is changed from  $0\text{V}$  to  $V_{DD}$ )? Explain briefly. [4 pts]

**Problem 4 (continued)**

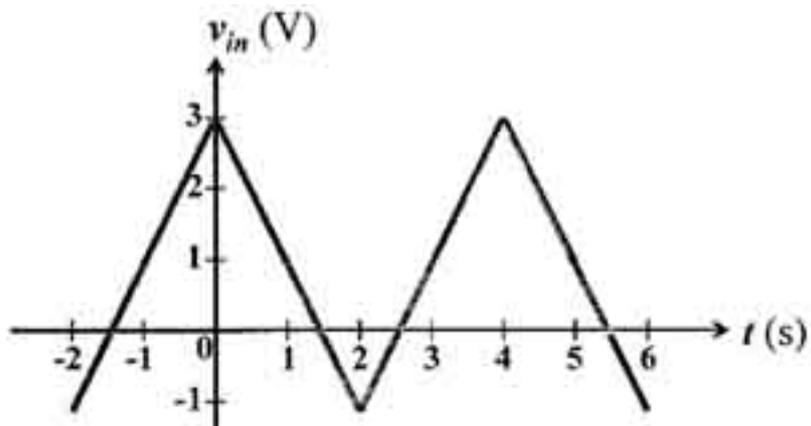
b) Consider the diode circuit below. Assume the diode is a perfect rectifier.



i) Plot  $v_{out}$  vs.  $v_{in}$  [5 pts]



iii) Sketch  $v_{out}$  for the given  $v_{in}(t)$ , using the same axes. [5pts]



**Problem 5: MOSFET [20 points in total]**

a) Consider an NMOSFET with parameters  $W = 1\mu\text{m}$ ,  $L = 0.1\mu\text{m}$ ,  $k_n' = 10^{-3}\text{A/V}^2$ ,  $V_T = 0.5\text{V}$ , biased at  $V_{GS} = V_{DD} = 1\text{V}$ . The areal gate capacitance  $C_{OX} = 3 \times 10^{-6}\text{F/cm}^2$ .

i) Accurately sketch the  $I_D$  vs.  $V_{DS}$  characteristic in the range  $0 \leq V_{DS} \leq 1\text{V}$ , neglecting velocity saturation and channel-length modulation. Indicate the numerical values for the saturation voltage ( $V_{DSAT}$ ) and current ( $I_{DSAT}$ ). **[6 pts]**

ii) Estimate the effective resistance of this MOSFET (for digital circuit applications).

(Again, assume that velocity saturation and channel-length modulation can be neglected.

**[3 pts]**

ii) On the same plot in part (i) above, accurately sketch and label the  $I_D$  vs.  $V_{DS}$  characteristic, taking into account that the electron velocity in the MOSFET channel saturates at  $10^7\text{cm/s}$ .

**[5 pts]**

**Problem 5 (continued)**

b) High drive current ( $I_{DSAT}$ ) is desirable for reduced equivalent resistance, to achieve smaller propagation delay to allow higher-speed circuit operation. Indicate in the table below how you would adjust various MOSFET parameters so as to increase  $I_{DSAT}$ . Briefly describe the tradeoff or disadvantage involved, if any, for each. (For example, the answer for gate length  $L$  is given.)

**[6 pts]**

MOSFET Parameter	To increase $I_{DSAT}$ , parameter must be	Associated tradeoff or disadvantage
Gate length $L$	decreased	Subthreshold leakage current increases, so that static power dissipation increases
Threshold voltage $V_T$		
Channel width $W$		

**Problem 6: Logic Circuits [20 points in total]**

a) Given the following truth table for the logic function **F**:

A	B	F
0	0	1
0	1	0
1	0	1
1	1	1

i) Write a simple logic expression for **F**. [2 pts]

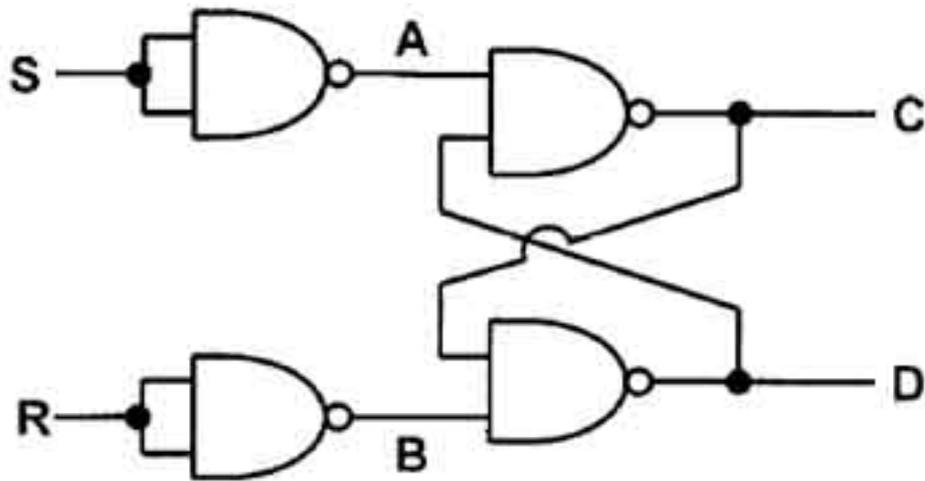
**F** = \_\_\_\_\_

iii) Implement the function **F**, using only 2-input NAND gates. [5 pts]

**Logic circuit for F:**

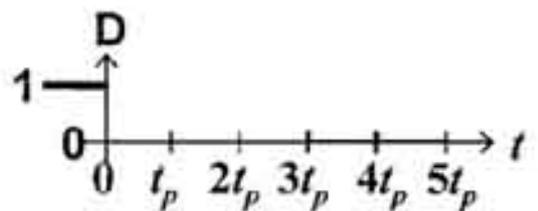
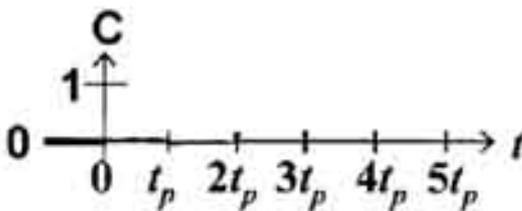
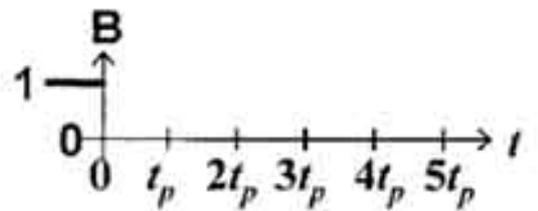
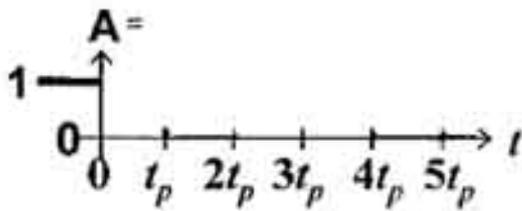
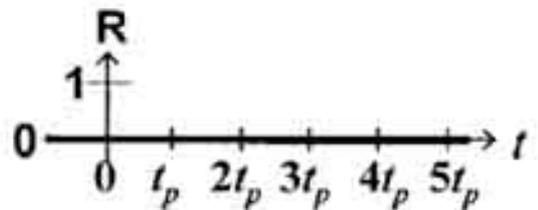
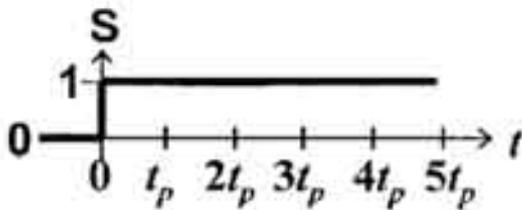
**Problem 6 (continued)**

b) Consider the S-R flip-flop circuit below:

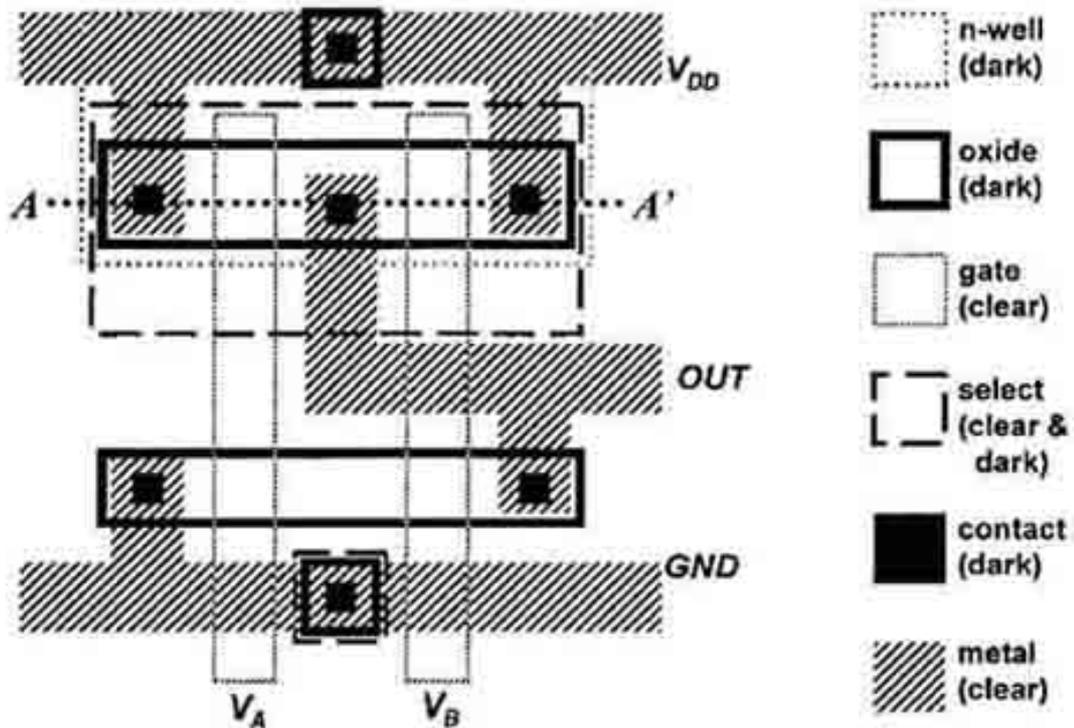


The output C is initially equal to 0, and the output D is initially equal to 1.

For the given S and R timing diagrams below, draw the timing diagrams (for  $t > 0$ ) for A, B, C, and D on the plots provided. [13 pts]



**Problem 7: CMOS Technology [20 points in total]**  
 The layout of a CMOS logic gate is shown below:

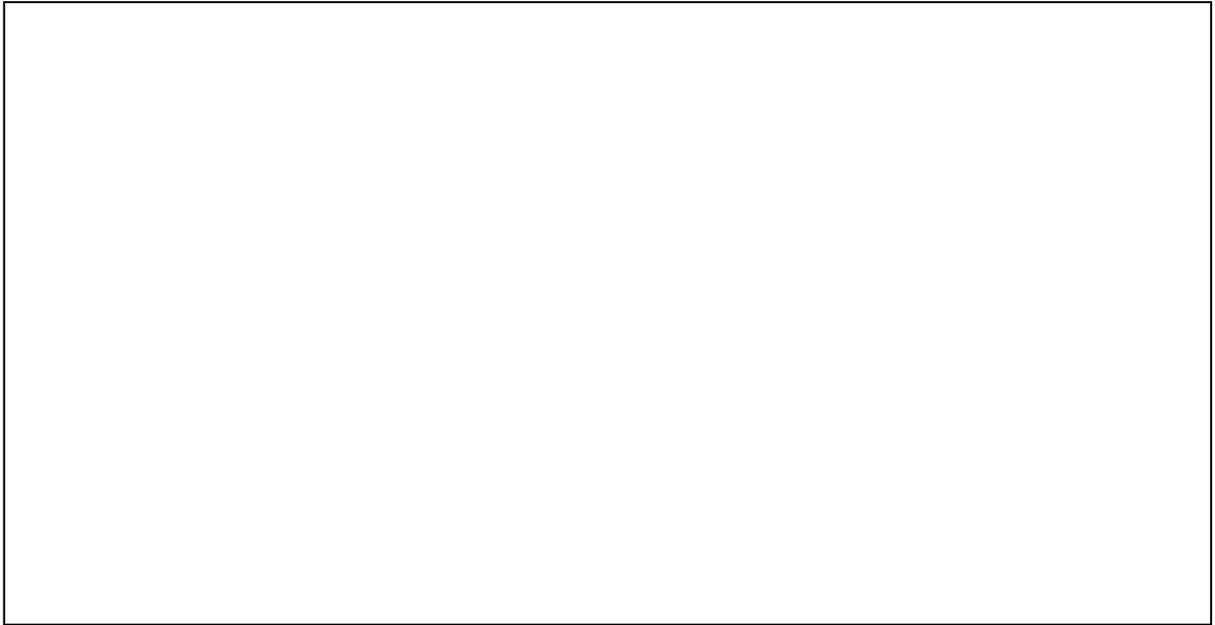


The following fabrication process (starting with a p-type Si wafer) is used:

1. Thermally grow 700 nm of  $\text{SiO}_2$ .
2. Pattern the  $\text{SiO}_2$  using the n-well mask.
3. Implant phosphorous and perform a high-temperature, long anneal to “drive in” the well to a depth of 1  $\mu\text{m}$ .
4. Remove the  $\text{SiO}_2$  (using a highly selective wet etch process which does not etch Si).
5. Grow 0.5  $\mu\text{m}$  of  $\text{SiO}_2$  (“field oxide”).
6. Pattern the  $\text{SiO}_2$  using the oxide mask.
7. Thermally grow 10 nm of  $\text{SiO}_2$  (“gate oxide”) in the bare regions of the Si.
8. Deposit 200nm of poly-Si (by CVD).
9. Pattern the poly-Si using the gate mask.
10. Use clear-field select mask to pattern photoresist; implant phosphorus. This will form the n+ source and drain junctions for the n-channel MOSDETs.
11. Use dark-field select mask to pattern photoresist; implant boron. This will form the p+ source and drain junctions for the p-channel MOSFETs.
12. Thermally anneal the wafer in order to activate the implanted dopants. The final source/drain junction depth is 100nm.
13. Deposit 0.5  $\mu\text{m}$  of  $\text{SiO}_2$  (“passivation oxide”).
14. Pattern the deposited  $\text{SiO}_2$  using the contact mask.
15. Deposit 0.5  $\mu\text{m}$  of aluminum.
16. Pattern the aluminum using the metal mask.

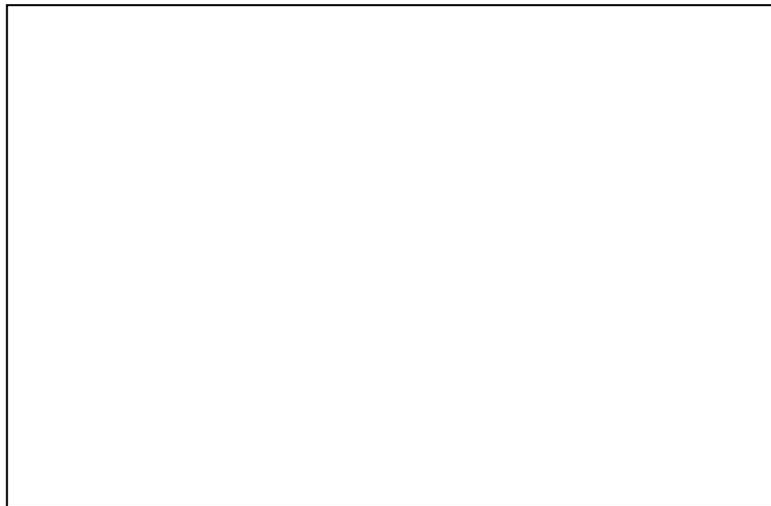
**Problem 7 (continued)**

a) Draw cross-section A-A' in the space provided. Identify all layers clearly. [10 pts]



**Cross-section A-A'**

b) Draw the circuit schematic, labeling  $V_{DD}$ , GND,  $V_A$ ,  $V_B$ , and OUT. [5 pts]



**Circuit Schematic**

c) Assuming that  $k_n' = 3k_p'$ , would you expect this logic gate to have comparable worst-case “pull-up” and “pull-down” propagation delays? (Is  $t_{pLH} \cong t_{pHL}$ ?) Justify your answer. [5 pts]

**Problem 8: Technology Scaling (Short-Answer Questions) [10 points in total]**

**a)** Explain how transistor scaling improves both the cost (per function) and performance (circuit operating speed) of CMOS integrated circuits. [5 pts]

**b)** Explain why interconnect delay is becoming more of a concern as CMOS technology advances. [5 pts]